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| 1. Record Nr. | UNINA9910456301303321 |
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| Titolo | Acoustic wave and electromechanical resonators : concept to key applications // Humberto Campanella |
| Pubbl/distr/stampa | Norwood, Massachusetts. : , : Artech House, , ©2010 [Piscataway, New Jersey] : , : IEEE Xplore, , [2010] |
| ISBN | 1-60783-978-4 |
| Descrizione fisica | 1 online resource (363 p.) |
| Collana | Integrated microsystems series |
| Disciplina | 621.381 |
| Soggetti | Acoustic surface wave devices Electric resonators Electronic books. |
| Lingua di pubblicazione | Inglese |
| Formato | Materiale a stampa |
| Livello bibliografico | Monografia |
| Note generali | Includes index. |
| Nota di bibliografia | Includes bibliographical references and index. |
| Nota di contenuto | 1. MEMs and NEMs resonator technologies -- 2. Acoustic microresonator technologies -- 3. Design and modeling of micro- and nanoresonators -- 4. Fabrication techniques -- 5. Characterization techniques -- 6. Performance optimization -- 7. Integration of resonator to CMOS technologies -- 8. Sensor applications -- 9. Radio frequency applications -- 10. Case studies. |
| Sommario/riassunto | This groundbreaking book provides you with a comprehensive understanding of FBAR (thin-film bulk acoustic wave resonator), MEMS (microelectromechanical system), and NEMS (nanoelectromechanical system) resonators. For the first time anywhere, you find extensive coverage of these devices at both the technology and application levels. This practical reference offers you guidance in design, fabrication, and characterization of FBARs, MEMS and NEBS. It discusses the integration of these devices with standard CMOS (complementary-metal-oxide-semiconductor) technologies, and their application to sensin. |